

00862.022199.



PATENT APPLICATION

8/A
C. Jones
12/1/03

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Keiji EMOTO

Application No.: 09/833,766

Filed: April 13, 2001

For: PIPE STRUCTURE, ALIGNMENT APPARATUS,
ELECTRON BEAM LITHOGRAPHY
APPARATUS, EXPOSURE APPARATUS,
EXPOSURE APPARATUS MAINTENANCE
METHOD, SEMICONDUCTOR DEVICE
MANUFACTURING METHOD, AND SEMI-
CONDUCTOR MANUFACTURING FACTORY

)
: Examiner: P. Rodriguez
)
: Group Art Unit: 2125
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: Confirmation No.: 4154
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) November 19, 2003
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Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

RECEIVED

NOV 25 2003

Technology Center 2100

AMENDMENT AND LETTER
FORWARDING SUBSTITUTE SPECIFICATION

Sir:

In response to the Official Action dated August 19, 2003, please amend the above-
identified application as follows:

11/21/2003 HLE333 00000040 09833766

01 FC:1201
02 FC:1202

688.00 OP
36.00 OP